

IN THE SPECIFICATION:

On page 8, line 23, please delete the paragraph beginning with "The optics" and insert the following paragraph:

11 The optics arrangement 107 includes first lens 111, mask 112, second lens 113, third lens 114, and fourth and fifth lens combination 115, comprising fourth lens 115a and fifth lens 115b. These lenses in the optics arrangement 107 shape and focus the light beams to fix at a desired spot size on the surface of the wafer 110. Dark Field Collection arrangement 116 is used in conjunction with Dark Field Narrow and Dark Field Wide channels.

IN THE CLAIMS:

Please amend claims 1 and 37 as follows:

1. (Thrice amended) A system for inspecting a specimen, comprising:
- an optical element arrangement for receiving light from a light generating device and imparting light toward said specimen and receiving a retro beam from said specimen;
 - a retro beam diversion element for diverting the retro beam from said optical element arrangement;
 - a multi-element sensing device for receiving and sensing retro beam position upon diversion from said optical arrangement, said multi-element sensing device comprising a plurality of linearly oriented sensing elements such that said retro beam is received by at least three of said sensing elements; and
 - a plurality of weighting elements corresponding to each of said plurality of sensing elements, wherein each of said weighting elements alters a characteristic of an electrical output of said corresponding sensing element based on a distance of said sensing element from a